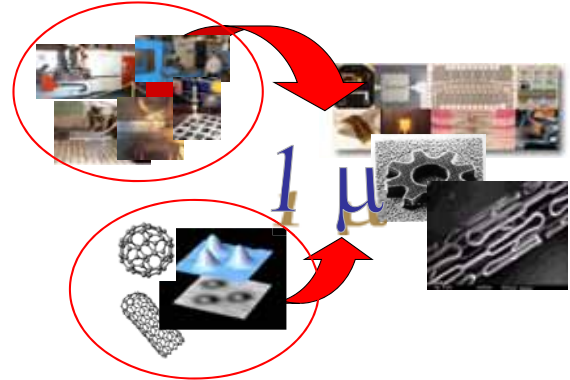


## Application of high intensity short pulse lasers to precision micromanufacturing

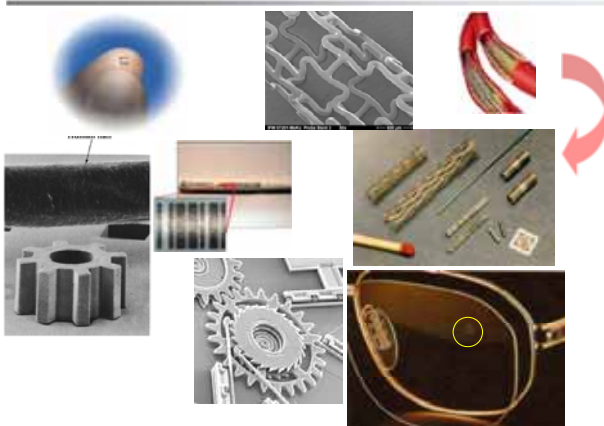
J.L. Ocaña, C. Molpeceres, M. Morales, M. Holgado, J.J. García-Ballesteros, S. Lauzurica, J.A. Porro, O. García, D. Iordachescu

ETSII-Dept. of Applied Physics and UPM Laser Centre  
Universidad Politécnica de Madrid  
ETSII-UPM, C/ José Gutiérrez Abascal, 2. E-28006 Madrid. SPAIN  
Tel.: (+34) 913363099. Fax: (+34) 913363000. email: jlocana@etsii.upm.es

### 1 $\mu\text{m}$ : LOOKING FOR SUITABLE FABRICATION TOOLS



### 1 $\mu\text{m}$ : LOOKING FOR SUITABLE FABRICATION TOOLS



### 1 $\mu\text{m}$ : MICRO-PROCESSING ADVANTAGES

1. High density of energy – required by very hard materials
2. Precision & repeatability
3. Enabled for high-selective ablation
4. Not intrusive – high flexibility noncontact machining
5. Very reduced HAZ

## LASER MICRO vs MACROMACHINING

Are laser systems going to play the same role in micro applications that they played in macro-processing?



- Clean processing to eliminate debris
- Flexibility - fast setups achievement
- Little or no burring or affected zones
- Fully 3D processing

- Close tolerance
- Excellent repeatability
- Unit cost reductions
- Material versatility



## LASER MICROMACHINING: A TECHNOLOGICAL INNOVATION?

*Micromachining means cutting, welding, soldering, selective ablation, forming, patterning, etc, with dimensional details in the order of 1  $\mu\text{m}$ .*

- Excimer photolithography and selective ablation ~ 20 years
- Semiconductor applications *dicing, drilling, engraving, cutting, etc.* in Si, TCOS, etc. ~ 20 years
- *ps* and *fs* lasers applications ~ 15 years
- DPSS Q-switch multi kHz sources ~ 10 years

## LASER MICROMACHINING FACTS

- Laser micromachining is intended mainly for material modification near the surface or for processing with high aspect ratios.
- Most present applications are **strictly 2D (planar or cylindrical) or are intended to process planar areas of 3D objects**. Presently an increasing interest in fully 3D applications is developing, and in general, implying some serious mechanical problems. These facts imply non trivial questions at the time of systems definition and design and, in particular, positioning systems characteristics and figures are of great transcendence, and not admitting simple scaled solutions from macroprocessing systems.

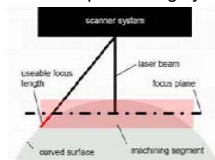
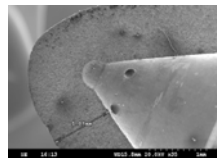


Fig. 4: Machining of a curved surface

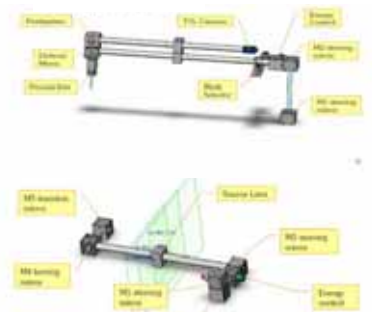


Thin Film and  
Surface Engineering



Fuel injector section

## CML-100



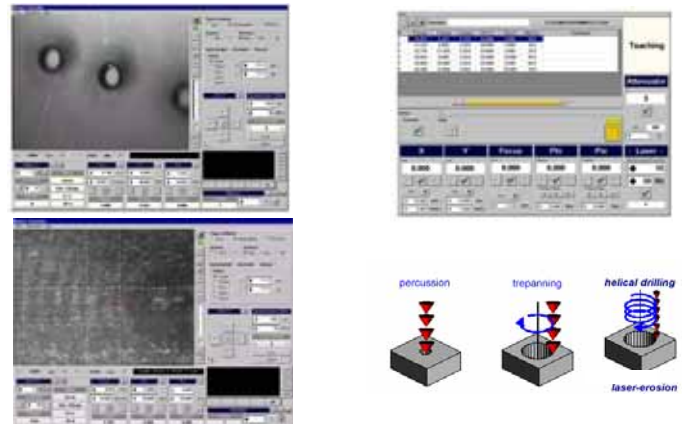
Multi-axis (6) system  
with *ns* laser sources for focal point applications,  
mask projection and hybrid techniques.

## LASER PARAMETERS

Laser Media	Excimer (KrF)	DPSS 3 $\omega$ (Nd: YVO <sub>4</sub> )	DPSS 1 $\omega$ (Nd: YAG)
Wavelength (nm)	248	355	1064
Pulse Duration (ns)	3-7 ns	< 12 ns (@ 50 kHz)	< 70 ns (@ 7.5 kHz)
Beam shape/mode	Rectangular (3.5 x 6 mm)	TEM <sub>00</sub> (M <sup>2</sup> < 1.3)	TEM <sub>00</sub> (M <sup>2</sup> < 1.15)
Operating frequency	0-300 Hz	15 – 300 kHz	1-100 kHz
Average power (W)	0.3-5 (@ 300 Hz)	5 W (@ 50 kHz)	6.5 W (@ 50 kHz)

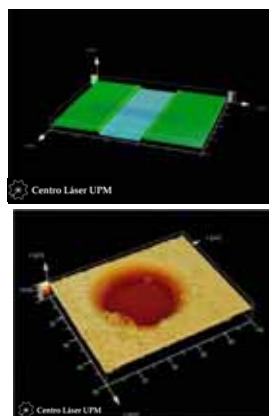
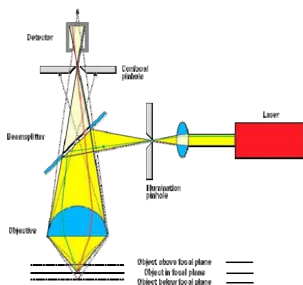
- DPSS (355 & 1064 nm): Focal point processing
- EXCIMER Irradiation (248 nm): Mask projection and hybrid techniques

## SOFTWARE FEATURES

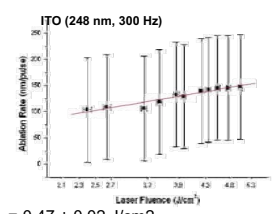
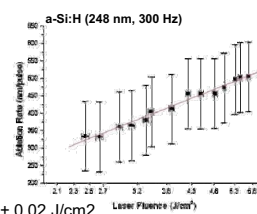
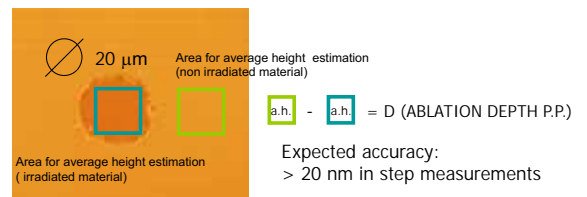


## WORKPIECE ANALYSIS AND MEASUREMENT

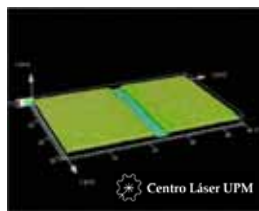
Confocal Laser Scanning Microscopy  
(Leica ICM 1000,  $\lambda=635$  nm)  
and SEM imaging



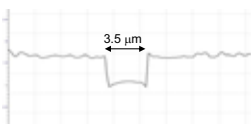
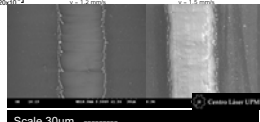
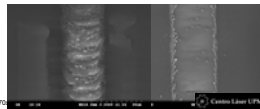
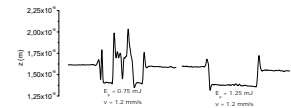
## ABLATION CURVES MEASUREMENT



## THIN FILM SELECTIVE ABLATION



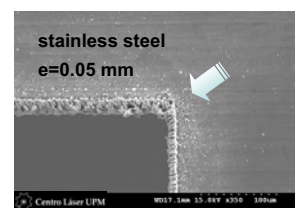
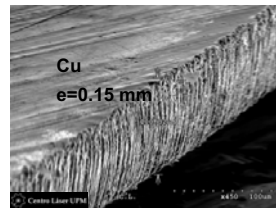
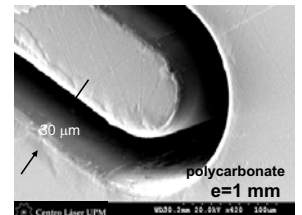
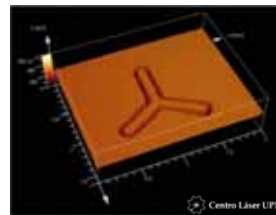
a-Si SELECTIVE ABLATION



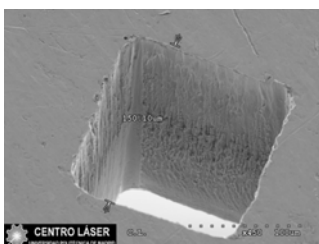
TCO SELECTIVE ABLATION

e=500 nm

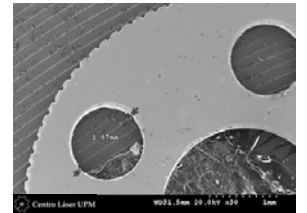
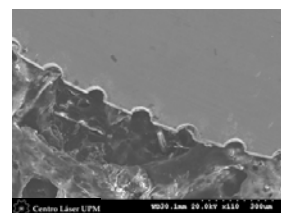
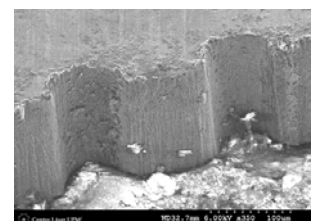
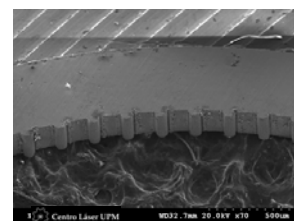
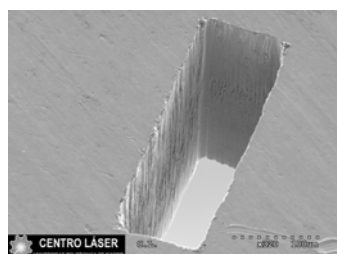
## PLANAR CUTTING APPLICATIONS



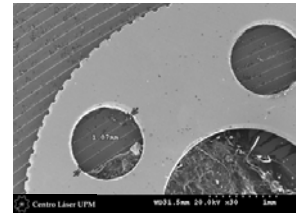
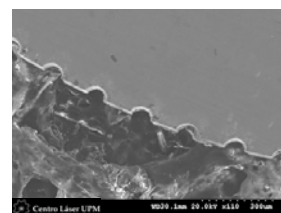
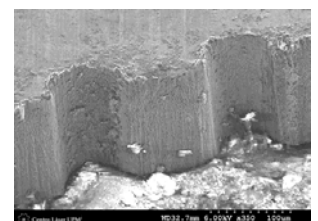
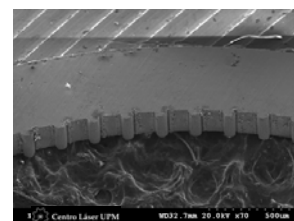
## PLANAR CUTTING APPLICATIONS



Mo  
e=0.2 mm

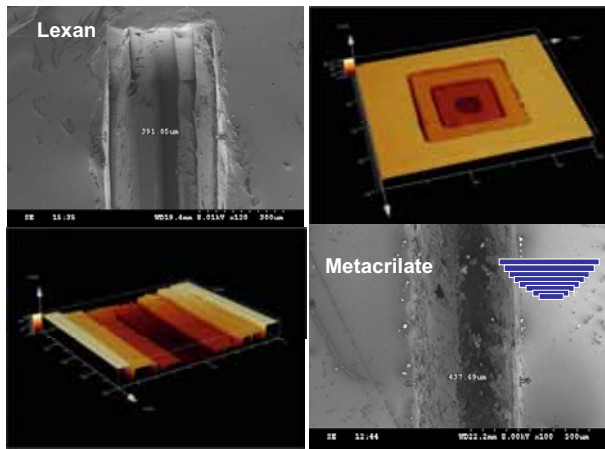


## MICROGEARS CUTTING

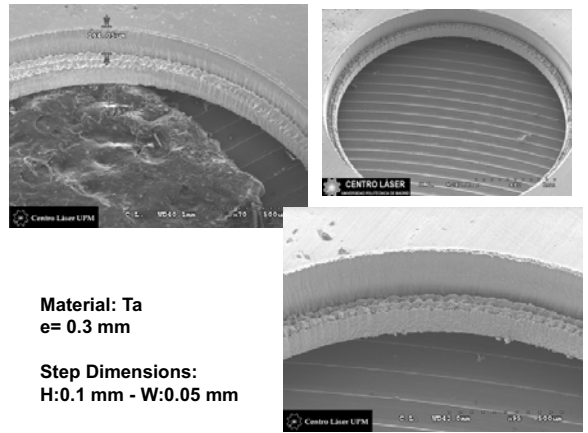




## MICROMILLING USING HYBRID TECHNIQUES

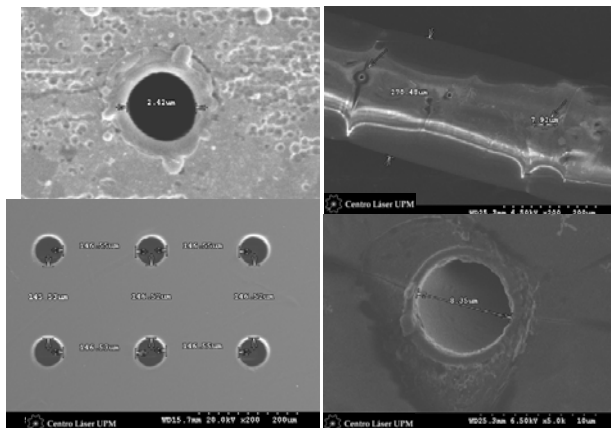


## MICROMILLING: STEP GENERATION FOR ASSEMBLING

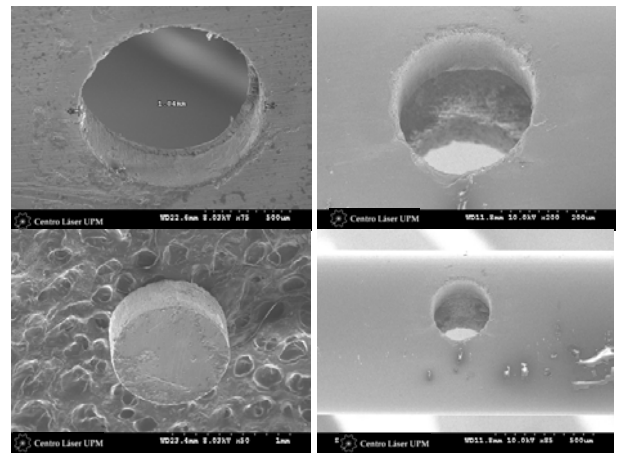


## 2D HOLE DRILLING

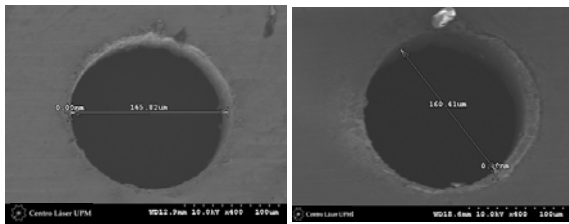
Planar Fused Silica Cylindrical



## 2D TREPPANNING



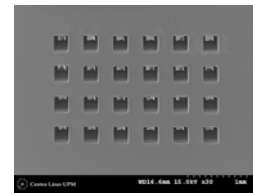
## 2D TREPPANNING



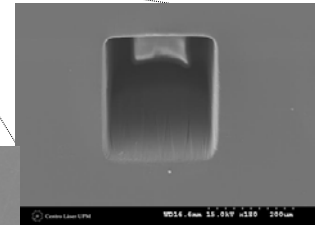
Steel: 1mm



## CHANNELS FABRICATION WITH COLATITUDE CONTROL ( $2 + \frac{1}{2} D$ )

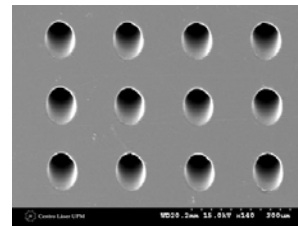


Polycarbonate

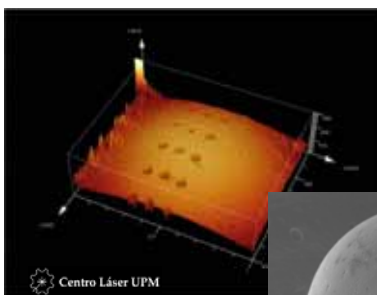


e=1 mm

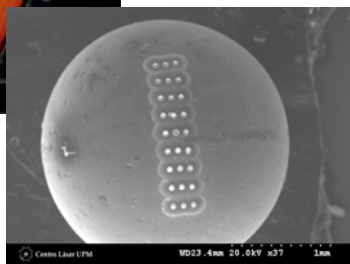
L= 250 μm  
 $\alpha = 30^\circ$   
Circular section



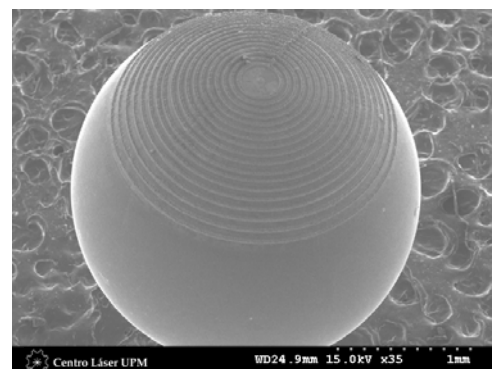
## 3D SURFACE TEXTURING



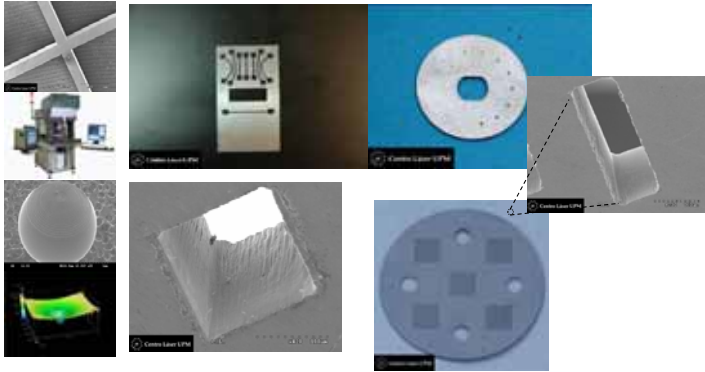
Sphere diameter = 2.5 mm  
 $\Phi = 75 \mu m$



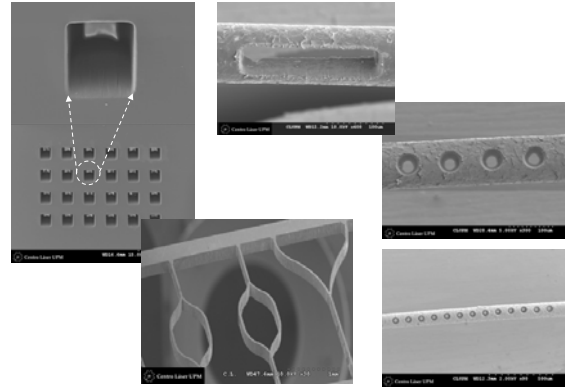
## 3D SURFACE TEXTURING



## MICROMACHINING EXAMPLES



## MICROMACHINING EXAMPLES



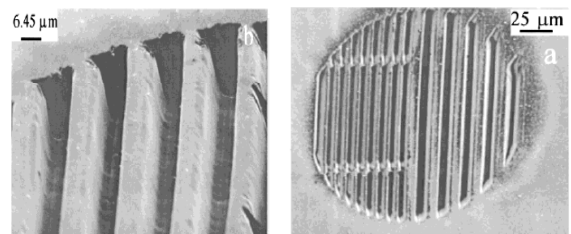
## MICROPROCESSING: CML-100

### CONCLUSIONS

- A prototype of a fully 3D flexible laser micromachining system has been designed and presently is completely operative
- Integration of excimer and DPSS UV laser in the same system has demonstrated to be an added value for this kind of equipment
- Complex geometries (concerning the workpiece and the pattern to be processed) have been obtained in different materials
- Nowadays there is an important demand for 2D and 2D + 1/2 applications and the appearance of fully 3D applications is expected for the next years

### Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

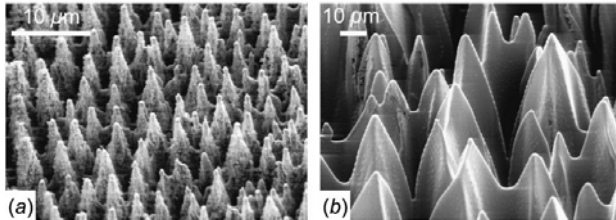
#### a. Laser surface microstructuring of polymeric surfaces



SEM micrographs of microstructures produced by a 20 ns pulse XeCl laser in different polymers : (a) structure in MP2C irradiated at 4.6 J cm<sup>-2</sup> with 9 pulses; (b) structure in TM2C irradiated at 4.6 J cm<sup>-2</sup> with 11 pulses.

## Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

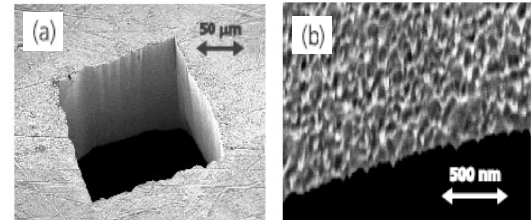
### b) Laser surface microstructuring of semiconductors



Microstructures formed in crystalline Si by laser pulses: a) Ti:Sapphire laser of 100 fs pulse length up to 10 kJ/m<sup>2</sup> fluence; b) KrF laser of 30 ns pulse length up to 30 kJ/m<sup>2</sup> fluence.

## Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

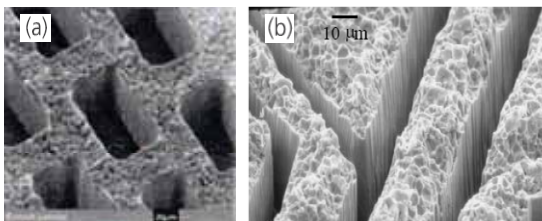
### c) Laser surface microstructuring of metals and metallic alloys



Microstructure generated in a stainless steel sheet with KrF laser radiation. a) Rectangular hole machined with 120-fs pulses at 1013 W/cm<sup>2</sup>; b) Magnified view of the microstructure of the exit edge of the exit edge of the same.

## Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

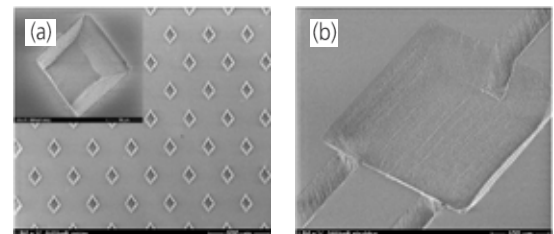
### d) Laser surface microstructuring of glass and ceramics (1/2)



Samples of laser microstructuring of ceramic materials with high aspect ratio using a mask projection technique with UV lasers: a) alumina b) PZT

## Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

### d) Laser surface microstructuring of glass and ceramics (2/2)

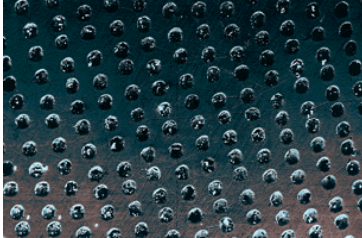


Laser generated structures in Pyrex® glass: a) Array of micro wells with 50 µm edge length and depth; b) cavity 350 x 350 x 55 µm<sup>3</sup> with channels: 50 µm width, 55 µm depth.



## Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

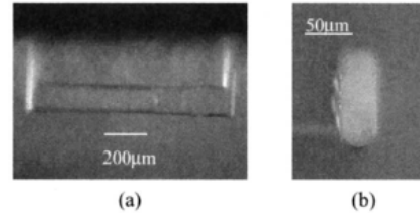
### e) Laser Surface Texturing



Regular micro-surface in the form of micro-dimples structured by ns laser.

## Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

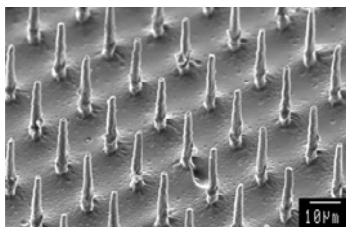
### f) 3D Laser glass microstructuring



3D Bridge-like microstructure generated by a 140 fs, 775 nm laser in Foturan®.

## Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

### g) Microstructuring by laser sintering and other techniques



Scanning electron micrograph showing a microscopic pillar array fabricated by casting a heat shrunk polymer template. (Courtesy of A.J. Lee et al.: Appl. Phys. A 80, 1447–1449, 2005)

## MICRO-FORMING

### LSPSIM PARAMETERS

Nd:YAG Laser [nm]	1064
Energy per pulse [mJ]	33 – 150
Pulse length [ns]	9.4
Spot Radius [μm]	175
Target	SS304
Confining medium	Air
Interaction parameter α	0.2

### ABAQUS PARAMETERS

Pressure Pulse	LSPSIM
Temporal Evolution	
Pressure Pulse	Top Hat
Spatial Distribution	
Spot Center Position	variable

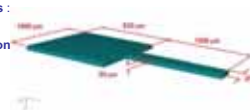
### MATERIAL PROPERTIES (SS304)

Young's Modulus: E [GPa]	193
Poisson's Coefficient: ν	0.25
Density: ρ [kg/m <sup>3</sup> ]	7896
Melting Temperature: T <sub>m</sub> [K]	1811
Test Temperature: T <sub>s</sub> [K]	300
Inelastic Heat Fraction: X	0.9
Johnson-Cook	
A [MPa]	350
B [MPa]	275
C	0.022
n	0.36
m	1
T <sub>1</sub> [K]	300
ε <sub>1</sub> [s <sup>-1</sup> ]	1

### GEOMETRY AND DIMENSIONS

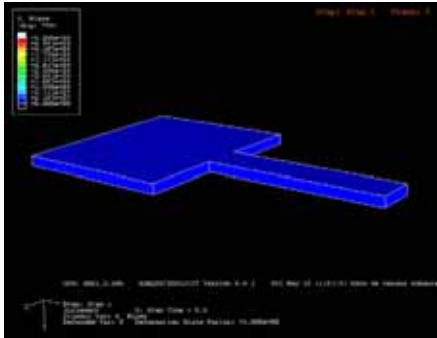
- Boundary Conditions :  
pinned end.

- Mechanical Simulation  
Elements: C3D8R, 8-  
node brick reduced  
integration with  
hourglass control



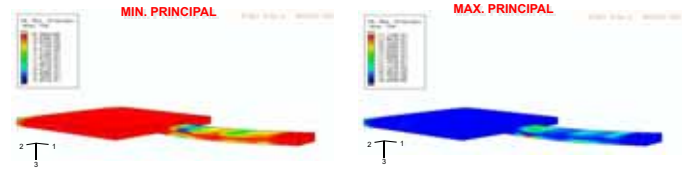
## MICRO-FORMING

### ABAQUS EXPLICIT – VON MISES EVOLUTION

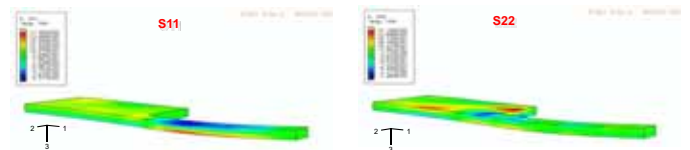


## MICRO-FORMING

### PLASTIC STRAIN



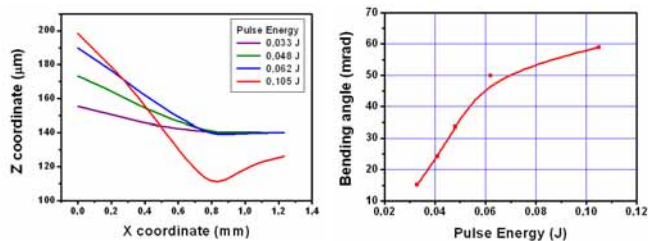
### STRESS DISTRIBUTION



## MICRO-FORMING

### Pulse Energy Parametric Dependency

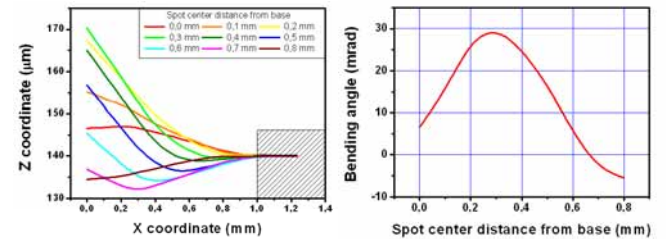
Nd:YAG Laser [nm]	1064	Material Model	SS304 = JC
Energy per pulse [mJ]	variable	Confining medium	Air
Pulse length [ns]	9.4	Interaction parameter $\alpha$	0.2
Spot Radius [ $\mu\text{m}$ ]	175	Spot center distance [ $\mu\text{m}$ ]	150



## MICRO-FORMING

### Spot Center Distance Parametric Dependency

Nd:YAG Laser [nm]	1064	Material Model	SS304 = JC
Energy per pulse [mJ]	33	Confining medium	Air
Pulse length [ns]	9.4	Interaction parameter $\alpha$	0.2
Spot Radius [ $\mu\text{m}$ ]	175	Spot center distance [ $\mu\text{m}$ ]	variable



## MICRO-FORMING

### EXPERIMENTAL SETUP

#### MicroForming Parameters

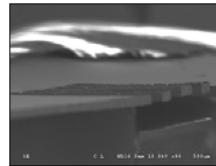
Nd:YAG Laser Wavelength [nm]	1064
Energy per pulse [J]	1.05
Pulse length FWHM [ns]	9.4
Beam radius (mm)	15
Mask radius [ $\mu\text{m}$ ]	750
Energy per pulse (after mask) [J]	0.033
Spot radius [ $\mu\text{m}$ ]	175
Confining layer	air



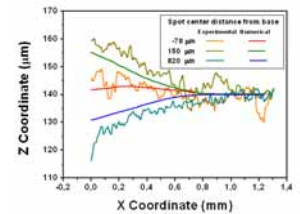
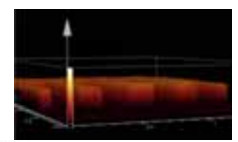
## MICRO-FORMING

### SPOT CENTER DISTANCE INFLUENCE

#### SEM IMAGES



#### CONFOCAL MICROSCOPY



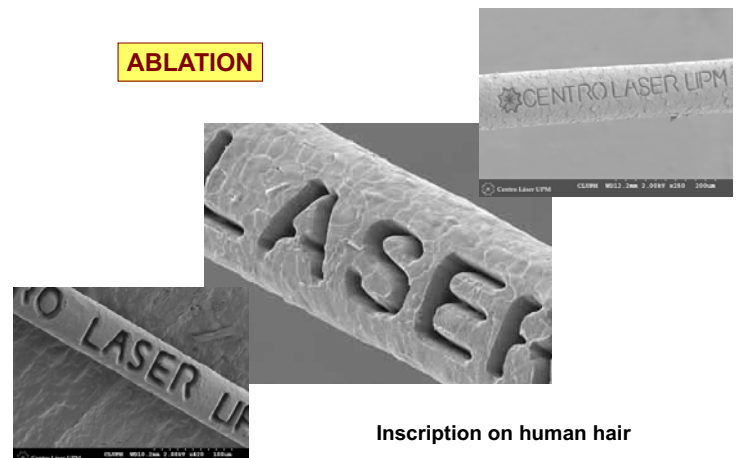
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## ABLATION



Inscription on human hair

# Thank you !